

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 05-166712

(43)Date of publication of application : 02.07.1993

(51)Int.Cl.

H01L 21/027

B05D 1/40

G03F 7/16

(21)Application number : 03-335061

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(22)Date of filing : 18.12.1991

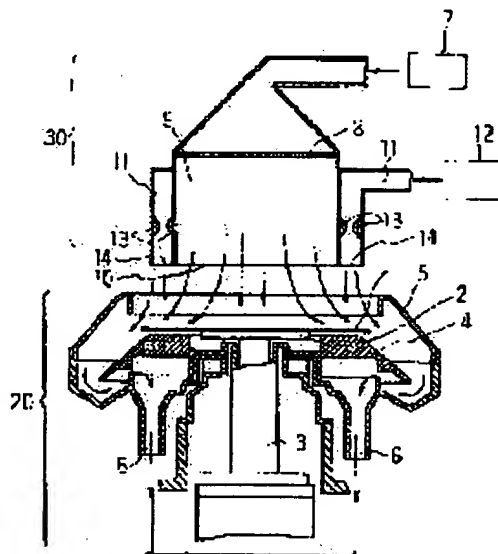
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(54) SPIN COATING METHOD

(57)Abstract:

PURPOSE: To form an even film by supplying a substrate with the air current so controlled that the temperature and humidity are different for each area divided along the rotational radial direction of the substrate.

CONSTRUCTION: An air current supply duct device 30 is provided with a cylindrical central part air current supply duct 9 which supplies around the central part on the surface of a wafer 1 with air current and a peripheral part air current supply duct 11 which supplies around the peripheral part on the surface of the wafer 1 with air current. One respective air current so controlled that the temperature and humidity are different is supplied to the wafer 1 from the central part air current supply duct 9 and the peripheral part air current supply duct 11 for forming a film of even thickness.



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